

	DAY 1: December 3, 2024 (Tuesday)
08:00am - 08:55am	Registration
Venue	Grand Ballroom
09:00am - 09:15am	Opening Ceremony
09:15am - 10:00am	Dr Vic Lin Jing-Cheng, EVP, Samsung Electronics
00.10am - 10.00am	KEYNOTE: Unleashing AI Power: The Hybrid Copper Bonding Technology for 3D System Integration, HBM and CPO
10:00am - 10:45am	Glenn G. Daves, Senior VP, NXP Semiconductors
10.00am - 10.40am	KEYNOTE: Packaging at the Emerging Edge
10:45am - 11:00am	Coffee/Tea Break (Grand Ballroom Foyer)
44.00 40.00	Panel Session: Asia's Role in the Global Semiconductor Industry (Moderator: Keat Yap, Kearney)
11:00am - 12:30pm	Panelist: Andrew Goh (Lam Research), Chan Pin Chong (Kulicke and Soffa)
12:30pm - 1:30pm	Lunch @ Grand Ballroom Foyer (Level 4)
Venue	Grand Ballroom
4.20	Dr Yu-Po Wang, VP, Siliconware Precision Industries Co., Ltd.
1:30pm - 2:15pm	KEYNOTE: Breaking Boundaries of IC Packaging through Innovative Integration Technology
0.45	Tim Olson, CEO, Deca Technologies
2:15pm - 3:00pm	KEYNOTE: Tectonic Forces Shaping the Future of the Semiconductor Industry
2.00	Dr Devan Iyer, Chief Strategist (Advanced Packaging), IPC International
3:00pm - 3:45pm	KEYNOTE: Advanced Packaging-Customization Trends and Standardization Opportunities
3:45pm - 4:00pm	Tea Break & Exhibition (Grand Ballroom Foyer)
4:00mm 5:20mm	Panel Session: The Role of Co-Packaged Optics in Advancing AI Technologies (Moderator: Matt Kelly/Dr Devan Iyer, IPC International Inc.)
4:00pm - 5:30pm	Panelist: Dr Masaki Kato (Marvell), Dr Torseten Wipiejewki (Huawei), Prof Subramanian S Iyer (UCLA), Dr Calvin Cheung (ASE) and PV Ramana (Lighspeed Photonics)
6:00pm - 8:00pm	VIP Dinner (by invitation only)



		DAY	2: December 4, 2024 (Wedne	sday)			
		Exhibition at	Waterfromnt Foyer from 8:30am to 5:3	30pm (Level 2)			
Venue	Veranda I	Veranda II	Veranda III	Riverfront I	Riverfront II	Riverfront III	
09:00am - 10:45am	PDC1: Chiplet, Heterogeneous Integration and Co-Packaged Optics	PDC2: Photonic Technologies for Communication, Sensing and Displays	PDC3: Wafer Bonding for Advanced Packaging Applications	PDC4: Current and Future Challenges and Solutions in AI & HPC	PDC5: Mechanics and Reliability of Lead-Free Solders Joints	PDC6: Failure Analysis of Advanced Packages: Fundamental, Skills, Philosophy & Case Studies	
	Dr John H. Lau Unimicron	Dr Torseten Wipiejewski Huawei	Dr Viorel Dragoi EV Group	Dr Refai-Ahmed Gamal AMD	Professor Jeff Suhling, Auburn Univeristy	Dr Yong-Fen Hsieh MA-Tek	
10:45am - 11:00am		Coffee/Tea Break					
11:00am - 12:30pm	PDC1 (cont'd)	PDC2 (cont'd)	PDC3 (cont'd)	PDC4 (cont'd)	PDC5 (cont'd)	PDC6 (cont'd)	
12:30pm - 2:00pm			EPS Luncheon @ Wate	rfront Ballroom (Level 2)			
2:00pm - 2:45pm	Professor Subramanian S. Iyer, Distinguished Professor, UCLA						
2.00pm - 2.40pm		KEYNOTE: Strategic Directions for Electronics Packaging					
2:45pm - 3:15pm		Dr Victor Zhirnov, Semiconductor Research Corporation (SRC) TECHNOLOGY TALK: New Roadmap for Microelectronics: Charting the Semiconductor Industry's Path Over the Next 5, 10, and 20 Years					
3:15pm - 4:15pm	R10 Chaper Chairs' Meeting (Verando I) Interactive Poster Presentation I / Exhibition / Coffee Break @ Waterfront foyer						
4:15pm - 6:00pm			Sponsors' Presentations & Luc	cky Draw @ Riverfront II and III			
6:00pm - 6:15pm			Transport to EPT	C Banquet Dinner			
6:15pm - 9:00pm			EPTC Banquet Dinner, RedDo	ot BrewHouse @ Dempsey Hill			



		Exhibition at	Waterfront Foyer from 8:30am to 5:30	0pm (Level 2)		
Venue	Veranda I	Veranda II	Veranda III	Riverfront I	Riverfront II	Riverfront III
	Invited Talk 1: James Papanu, Tokyo Electron Limited	Invited Talk 2: Tan Yik-Yee, Yole Group	Invited Talk 3: Sidina Wane, eV-Technologies	Invited Talk 4: Chan Pin Chong, Kulicke & Soffa	Invited Talk 5: Chai Tai Chong, IME	Invited Talk 6: Hardik Kabaria, Vinci4
09:00am -09:30am	D2W Hybrid & Fusion Bonding to Enable Adv Packaging (P1313)	Glass Core Substrate Market and Opportunity	Smart Integrated Electromagnetic Skins	Fluxless TCB for Chiplet Integration	RDL-First Interposer Technology for Next Generation Advanced Packaging	Towards Al-Assisted Design of Thermal Manageme
09:30am -10:30am	A1. Hybrid and Fusion Bonding 1	A2. Wafer Processing and Characterization	A3. Emerging Technologies I	A4. Advanced Packaging 1	A5. TSV and Wafer Level Packaging 1	A6. Thermal Management and Characteriz
	A1.1 (P1187) Improved Edge Detection Algorithm for Blurred Alignment Marks in Hybrid Bonding	A2.1 (P1412) Comprehensive Die Strengths Comparisons for Glass using Different Singulation Methods	A3.1 (P1367) Trade-off between Chiplet Dimensions and Packaging Parameters for Optimal cost-performance for Chiplet Based Heterogenous Integration	A4.1 (P1262) Dual Damascene process for 500nm RDL using High Resolution Photosensitive Polymer	A5.1 (P1344) Accelerating Overlay Error Optimization in Fine-Pitch Wafer-to-Wafer Hybrid Bonding through ML	A6.1 (P1136) Thermal Design and Analysis of a Flip-C HEMT
09:30am - 09:50am	Sugiura, Takamasa (1); Nagatomo, Daisuke (1); Kajinami, Masato (1);Ueyama, Shinji (1):Tokumiya, Takahiro (1):Oh, Seungyeol (2);Ahn, Sungmin (2);Choi, Euisun (2);Woo, Siwoong (2);Lee, Hyunjin (2);Lee, Byungion (2);Rhee, Minwoo Daniel (2)	Wei, Frank	Zhai, Max (1); Sahoo, Krutikesh (2); Iyer, Subramanian (2)	Gerets, Carine Helena; Pinho, Nelson; Tseng, Wen Hung; Paulus, Tinneke; Labyedh, Nouha; Beyer, Gerald; Miller, Andy; Beyne, Eric	James, Ashish (1); Venkataraman, Nandini (2); Miao, Ji Hong (2); Singh, Navab (2); Li, Xiaoli (1)	Feng, Huicheng; Zhou, Lin; Tang, Gongyue; Wai, Eva L Teck Guan
	Samsung Japan Corporation (1)	DISCO Corporation, USA	UCLA, USA (2)	IMEC, Belgium	Institute for Infocomm Research, Singapore (1)	Institute of Microelectronics, Singapore
	A1.2 (P1195) Post-CMP Clean Optimization for SiCN Hybrid Bonding Applications	A2.2 (P1388) 200mm Reconstituted Wafer for Fan-out of Microfluidics and CMOS Electronics	A3.2 (P1253) Feasibility and Performance of Fully Additive Manufactured Light Bulbs	A4.2 (P1342) ECC-based Flux Cleaning Monitoring for Improved Reliability in Advanced Packaging Products	A5.2 (P1373) Study of Direct Copper Electroplating on Ruthenium Seed Layer for TSV Processes at 300mm Wafer Level	A6.2 (P1163) Silicon-Based Micro-Fluid Cooler Packag High Performance Computing
09:50am - 10:10am	JI, Hongmiao (1); LEE, Chaeeun (1);TEE, Soon Fong (1);TEO, Wei Jie (1);TAN, Geo Oon (1);Vonktaraman, Nandini (1);Lianto, Prayudi (2);TAN, Avery (2);LIE, Joselyn (2);SUM, Darren (2);SEOW, Kevan (2);CHEOK, Kelvin (2);CHONG, Hol Jin (2);TAMBOLJ, Dryanesh (3);TEO, Meivin (3)	Wei, Wei; Zhang, Lei; Tobback, Bert; Visker, Jakob: Stakenborg, Tim; Karve, Gauri; Tezcan, Deniz Sabuncuoglu	Ankenbrand, Markus; Piechulek, Niklas; Franke, Jörg	Wang, Yusheng; Huang, Baron; Lin, Wen-Yi; Zou, Zhihua; Kuo, Chien-Li	Tran, Van Nhat Anh; Venkataraman, Nandini; Tseng, Ya-Ching; Chen, Zhixian	Han, Yong; Tang, Gongyue; Lau, Boon Lo
	Institute of Microelectronics, Singapore (1)	IMEC, Belgium	Friedrich-Alexander Universität Erlangen Nürnberg, Germany	TSMC, Taiwan	Institute of Microelectronics, Singapore	Institute of Microelectronics, Singapore
	A1.3 (P1369) Maximizing Productivity through Bonding Sequence Optimization in the Chip on Wafer Process	A2.3 (P1332) Diffraction Alignment Sensor and Mark Design Optimization to Enable Fine Overlay Accuracy for 50 um Thick Si Bonded to Glass	A3.3 (P1377) Innovations and Challenges in Laser Direct Structured Mechatronic Integrated Devices for Aviation	A4.3 (P1256) Defluxing in Advanced Packaging: Critical Process Considerations and Solutions	A5.3 (P1227) Utilizing Ensemble Learning on Small Database for Predicting the Reliability Life of Wafer-Level Packaging	A6.3 (P1103) Power Management IC device Efficiency a
10:10am - 10:30am	Kim, Junsang (1);Yun, Hyeonjun (1);Kang, Mingu (1);Cho, Kwanghyun (1);Cho, Hansung (1);Kim, Yunha (1);Moon, Buriki (1);Rhee, Minwoo (1);Jung, Youngsook (2);Lee, Byungjoon (1);Kwon, Ohwoon (2);Joung, Geewoong (2);Kim, Jisu (1);Lee, Jungchul (2)	Tamaddon, Amir-Hossein (1); Jadli, Imene (1); Suhard, Samuel (1); Jourdain, Anne (1); Hsu, Alex (2); Schaap, Charles (2): De Poortere, Etienne (2): Miller, Andy (1); Kennes, Koen (1); Blanco, Victor (1)	Piechulek, Niklas; Ankenbrand, Markus; Xu, Lei; Fröhlich, Jan; Nguyen, Huong Giang; Franke, Jörg	Parthasarathy, Ravi	Su, Qinghua (1); Yuan, Cadmus (2); Chiang, Kuo-Ning (1)	Ge, Garry; Xu, L.Q.; Zhang, Bruce; Zeng, D
	Samsung Electronics, South Korea (1)	IMEC, Belgium (1)	Lehrstuhl für Fertigungsautomatisierung und Produktionssystematik	ZESTRON Americas	National Tsing Hua University, Taiwan (1)	NXP Semiconductor Company, China
10:30am - 10:45am			Tea Break & Exhibition (Vaterfront Ballroom Foyer)		
Venue	Veranda I	Veranda II	Veranda III	Riverfront I	Riverfront II	Riverfront III
10:45am -11:45am	B1. Hybrid and Fusion Bonding 2	B2. Interconnection Technologies 1	B3. Thermal Interface Materials	B4. Advanced Packaging 2	B5. Assembly and Manufacturing Technology 1	B6. Thermal Management and Characteriza
	B1.1 (P1211) Next Generation of Thermo Compression Bonding Equipment	B.2.1 (P1221) Study of Solder Bump and Joint Standoff Height Profiles Using Empirical and Numerical Methods	B3.1 (P1113) Evaluation of TIM Cross-Sectioning Methods on Lidded High-Performance Microprocessors	B4.1 (P1357) Investigation of UBM/RDL Contact Resistance Based on ICP Sputter Etch Conditions and Critical Design Dimensions	B5.1 (P1230) Investigation Of Multi Beam Laser Grooving Process And Die Strength for 55nm Code Low-k Wafer	B6.1 (P1274) Real-time Evaluation of Effective Therm Profile for the Redistribution Layer (RDL
10:45am - 11:05am	Abdilla, Jonathan	Wang, Yifan; Yeo, Alfred; CHAN, Kai Chong	Neo, Shao Ming; Song, Mei Hui; Tan, Kevin Bo Lin; Lee, Xi Wen; Oh, Zi Ying; Foo, Fang Jie	Carazzetti, Patrik (1); Drechsel, Carl (1); Haertl, Nico (1); Weichart, Jürgen (1); Viehweger, Kay (2); Strolz, Ewald (1)	Xia, Mingyue; Wang, Jianhong; Xu, Sean; Li, guangming; Liu, haiyan; Zhu, lingyan	Liu, Jun; Li, Yangfan; Cao, Shuai; Sridhar,
	Besi, The Netherland	STATS ChipPac, Singapore	AMD, Singapore	Evatec AG, Switzerland (1)	NXP, China	IHPC, A*STAR, Singapore
	B1.2 (P1316) Parylene as an adhesive for wafer and chip bonding as wel as for applications in wafer level packaging	B2.2 (P1134) Solder Ball Alloy Effect on Board Level Reliability Thermal Cycling and Vibration Test Enhancement	B3.2 (P1125) Analysis of Indium-Silver Alloy Thermal Interface Material Reliability and Coverage Degradation Mechanisms	B4.2 (P1389) Precise Wavelength Control in Fabry-Perot Filters using Thin Etch Stop Layers	B5.2 (P1215) An Optimization Study with Batch Microwave Plasma On Extra	B6.2 (P1282) POD-ANN Thermal Modelling Framew Thermal Analysis of 2.5D Chiplet Design
11:05am - 11:25am	Selbmann, Franz (1,2); Kühn, Martin (1,2); Roscher, Frank (1); Wiemer, Maik (1); Kuhn, Harald (1,3); Joseph, Yvonne (2)	Chen, Fa-Chuan (1); Yu, Kevin (1); Lin, Shih-Chin (1); Chu, Che-Kuan (2); Lin, Tai-Yin (2); Lin, Chien-Min (2)	Park, Donghyeon	Babu Shylaja, Tina; Tack, Klaas; Sabuncuoglu Tezcan, Deniz	LOO, Shei Meng; LEONE, Federico; CAICEDO, Nohora	Li, Yangfan; Liu, Jun; Cao, Shuai; Sridhar, Naraya
	Fraunhofer Institute for Electronic Nano Systems, Germany (1)	Mediatek, Taiwan	Amkor, Korea	IMEC, Belgium	STMicroelectronics, France	IHPC, A*STAR, Singapore
	B1.3 (P1368) Process Development of Chip to Wafer Hybrid Bonding with Polymer Passivation	B2.3 (P1185) Navigating the Optimal Material Selection for RF Transmission Lines in Cryogenic Systems	B3.3 (P1225) Selection of Non-clean Flux for Metal TIM	B4.3 (P1348) Packaging technology for Sub-terahertz antenna in module	B5.3 (P1255) In-situ Characterization of Plasma Species for Process Optimization and Improvement	B6.3 (P1171) Effect of Contact Characteristics on The Resistance of Grease-less Uniform Contact St
11:25am - 11:45am	Xie, Ling	Lau, Daniel (1); Bhaskar, Vignesh Shanmugam (1); Ng, Yong Chyn (1); Zhang, Yiyu (2); Goh, Kuan Eng Johnson (2); Li, Hongyu (1)	Li, Dai-Fei; Teng, Wen-Yu; Hung, Liang-Yih; Kang, Andrew; Wang, Yu-Po	Murayama, Kei (1); Taneda, Hiroshi (1); Tsukahara, Makoto (1); Hasaba, Ryosuke (2); Morishita, Yohei (2); Nakabayashi, Yoko (1)	Chou, Djamila; Capellaro, Laurence; Caicedo, Nohora	Aoki, Hirotoshi (1); Fushinobu, Kazuyoshi (2); Tomimi
	Institute of Microelectronics, Singapore	Institute of Microelectronics, Singapore	Siliconware Precision Industries Co., Ltd., Taiwan	Shinko Electric Industries Co.,Ltd, Japan (1)	STMicroelectronics, France	KOA Corporation, Japan (1)



DAY 3: December 5, 2024 (Thursday PM)						
		Exhibition at	Waterfront Foyer from 8:30am to 5:30	0pm (Level 2)		
Venue	Veranda I	Veranda II	Veranda III	Riverfront I	Riverfront II	Riverfront III
1:00pm - 2:00pm	C1. Electrical Simulations & Characterization 1	C2. Wireless and Antenna Package Designs	C3. Materials and Processing 1	C4. Mechanical Simulation & Characterization 1	C5. TSV and Wafer Level Packaging 2	C6. Thermal Management and Characterization 3
	C1.1 (P1108) Signal integrity analysis of dense wire channels on 2.5D substrate technologies for UCle and BOW applications	C2.1 (P1397) A Compact 1x4 Antenna Array with Steerable Beam for 5G millimeter-Wave Smartphone Applications	C3.1 (P1159) Photosensitive aqueous alkaline developable magnetic material for inductor and balun transformers in 3D WLP	C4.1 (P1324) Copper balance and wafer level warpage control and effect of package stress and board-level TC solder joint reliability	C5.1 (P1396) Advantages of Digital Lithography in Patterning of UHD FoWLP Utilizing Novel PI Dielectrics	C6.1 (P1354) Efficient Thermal-Aware Floor-planning with Bayesian Optimization: A Simulation-Efficient Approach
1:00pn - 1:20pm	Rotaru, Mihai Dragos	Hsieh, Sheng-Chi	Masuda, Seiya; Idei, Hiroaki; Miyata, Tetsushi; Oi, Shota; Suzuki, Hiroyuk	a Mandal, Rathin	Varga, Ksenija	Hegedüs, János; Takács, Dalma; Hantos, Gusztáv; Poppe, András
	Institute of Microelectronics, Singapore	ASE Group, Taiwan	FUJIFILM Corporation, Japan	Institute of Microelectronics, Singapore	EV Group, Austria	Institute for Infocomm Research, Singapore
	C1.2 (P1161) Design of Underground Structure Cover with Self- Complementary Slits for Wireless Telecommunication Application	C2.2 (P1139) Development of 2.4GHz band L-shaped Circular Polarized slot antenna	C3.2 (P1118) New DA Adhesive Meets Challenging Performance, Reliability and Cost Objectives of Automotive MCU Packaging	C4.2 (P1340) Material sensitivity of a fan-out package warpage – simulations and experimental validation	C5.2 (P1193) Chip to Wafer and Wafer to Wafer Density estimation and Design rules physical verification.	C6.2 (P1343) Optimizing Chiplet Placement in Thermally Aware Heterogeneous 2.5D Systems Using Reinforcement Learning
1:20pm - 1:40pm	Rong, Zihao (1); Yi, Yuantong (1); Tateishi, Eiichi (2); Kumagae, Takaya (2); Kai, Nobuhiro (2); Yamaguchi, Tatsuya (3); Kanaya, Haruichi (1)	Suehiro, Kazuki; Nakashima, Kenta; Kanaya, Haruichi	Kang, Jaeik; Hong, Xuan; Zhuo, Qizhuo; Yun, Howard; Shim, Kail; Rathnayake, Lahiru; Surendran, Rejoy; Trichur, Ram	Tippabhotla, Sasi Kumar; Soon Wee, David Ho	Mani, Raju; Dutta, Rahul; Cheemalamarri, Hemanth Kumar; Vasarla Nagendra, Sekhar	Kundu, Partha Pratim (1); Furen, Zhuang (1); Sezin, Ata Kircali (1); Yubo, Hou (1); Dutta, Rahul (2); James, Ashish (1)
	Kyusu University, Japan (1)	Kyushu University, Japan	Henkel, USA	Institute of Microelectronics, Singapore	Institute of Microelectronics, Singapore	Institute for Infocomm Research, Singapore (1)
	C1.3 (P1167) Equivalent Electromagnetic Radiation Model of Chip Based on Near-Field Scanning for EMI Analysis in Ceramic SiP	C2.3 (P1203) Development of Long-Range Wireless Energy Harvesting Circuit by Multistage Cockcroft-Walton Circuit	C3.3 (P1246) Doped SAC Solder Ball Alloys Comparison for High Performance Automotive BGA Packages	C4.3 (P1147) Advanced Prediction Model for SACQ Solder Reliability Assessment for Automotive Memory Applications	C5.3 (P1374) Panel Level Fine Patterning RDL Interposer Package	C6.3 (P1259) From Package Thermal Measurements to Material Characterization: A Remote Phosphor Aging Test
1:40pm - 2:00pm	Liang, Yaya; Du, Pingan	Tagawa, Nobuya; Hosaka, Ryoma; Tanaka, Hayato; fGoodwill, Kumar; Kanaya, Haruichi	Grolier-lee, Stelliane (1); Capellaro, Laurence (1); Mon, Aye aye (2); Wong, Kim-Sing (2); Loh, Hung-Meng (2); Caicedo, Nohora (1)	Pan, Ling (1); Che, Faxing (1); Ong, Yeow Chon (1); Yu, Wei (1); Ng, Hong wan (1); Kumar, Gokul (2); Fan, Richard (3); Hsu, Pony (3)	Park, Jieun; Kim, Dahee; Choi, Jaeyoung; Park, Wooseok; Choi, Younchan; Lee, Jeongho; Choi, Wonkyoung	Zhuang, Furen (1); Pratim Kundu, Partha (1); Kircali Sezin, Ata (1); Hou, Yubo (1); Dutta, Rahul (2); James, Ashish (1)
	UESTC, China	Kyushu University, Japan	STMicroelectronics, France (1)	Micron Semiconductor Asia Operations, Singapore (1)	Samsung Electronics, South Korea	Budapest University of Technology and Economics (1)
2:00pm - 3:00pm		Interactive Poster Presentation II / Exhi	bition / Coffee Break @ Waterfront foyer			
3:00pm - 4:20pm	D1. Electrical Simulations & Characterization 2	D2. Interconnection Technologies 2	D3. Materials and Processing 2	D4. Mechanical Simulation & Characterization 2		
	D1.1 (P1272) Crosstalk Analysis for Symmetric and Asymmetric High- Speed Signal Lines of GDDR6 Package	D2.1 (P1146) Assembly of Multi-Device Power Package with Clips as Interconnects	D3.1 (P1137) Novel Residue free High Lead Solder Paste for Power discrete	D4.1 (P1205) Impact of Structural Parameters on the Warpage of fcBGA Packages with Indium Thermal Interface Material		
3:00pm - 3:20pm	Jaiswal, Anushruti (1); Krishna, Vamsi (1); Dhanekula, Mahesh Babu (1); Desmond Dsilva, Hansel (2)	Wai, Leong Ching; Yeo, Yi Xuan; Soh, Jacob Jordan; Tang, Gongyue	Bai, Jinjin; Li, Yanfang; Liu, Xinfang; Chen, Fen; Liu, Yan	Liu, Zhen (1); Dai, Qiaobo (1); Nie, Linjie (1); Xu, Lanying (1); Teng, Xiaodong (1); Zheng, Boyu (1,2)		
	Ansys, India (1)	Institute of Microelectronics, Singapore	Indium, China	Changsha AnMuQuan Intelligent Technology, China (1)		
	D1.2 (P1355) Signal Integrity Simulation and Analysis for 2.5D Advanced Package Interconnect Based on UCIe	D2.2 (P1129) Characterization of Recycleed Gold Bonding Wire on Memory Package	D3.2 (P1220) Low Flux Residue No-Clean Solder Paste for System-in- Package (SiP) Application	D4.2 (P1141) Impact of Package Warpage on Package Strength Assessment under Three-Point Bending Test Condition		
3:20pm - 3:40pm	Fan, Yuxuan (1,2); Gan, Hanchen (1,2); Zhou, Yunyan (1); Lei, Bo (1); Song, Gang (1); Wang, Qidong (1)	Chen, Yi-jing; Zou, Yung-Sheng; Chung, Min-Hua; Gan, Chong-Leong	Liu, Xinfang; Bai, Jinjin; Chen, Fen; Liu, Yan	Che, Fa Xing (1); Ong, Yeow Chon (1); Yu, Wei (1); Pan, Ling (1); Ng, Hong Wan (1); Kumar, Gokul (2); Takiar, Hem (2)	Heteregeous Integration Roadmaps	(HIR) Workshop (3:15pm to 5:20pm)
	IMECAS, China (1)	Micron, Taiwan	Indium, China	Micron Semiconductor Asia Operations, Sinagpore (1)		
	D1.3 (P1223) Effect of Mesh Ground Plane on Impedance Control and Crosstalk of Organic Interposers Targeted for Chiplet Applications	D2.3 (P1126) Investigation of the Electromigration Behaviour of Solder Bump under Different Conditions	D3.3 (P1176) Analysis of Basic Properties and Bonding Properties of Various Melting Temperature Solders	D4.3 (P1181) Evaluation of Thermo-mechanical Fatigue life of Microvias under PCB Substrate's influence during Reflow Process		
3:40pm - 4:00pm	Lim, Ying Ying (1); Nemoto, Shunsuke (2)	Law, Yi Kei Owen (1); Fan, Haibo (1); Zhong, Chenchao Nick (1); Shi, Yuning (2)	Kim, Hui Joong; Lee, Jace; Lee, Seul Gi; Son, Jae Yeol; Won, Jong Min; Park, Ji Won; Kim, Byung Woo; Shin, Jong Jin; Lee, Tae Kyu	Syed, Mujahid Abbas; Yu, Qiang		
	National Institute of Advanced Industrial Science and Technology, Japan (1)	Nexperia, Hong Kong	MKE, South Korea	Yokohama National University, Japan		
	D1.4 (P1241) Development of Compact Wideband Balun using Multilayer Substrate-integrated Coaxial line	D2.4 (P1168) Investigation of NiSn4 formation in the Relation between SnBi Solder and ENEPIG Substrate	D3.4 (P1124) A Novel Method for PBO Adhesion Characterization in WLCSP Package	D4.4 (P1160) Improved Thermal performance of 3D Opto-Electronic IC assembled on multiple Interposers through design optimization		
4:00pm - 4:20pm	Sato, Takumi (1); Kanaya, Haruichi (1); Ichirizuka, Takashi (2); Yamada, Shusaku (2)	Wang, YI-Wun; Tsai, Cheng-Ting; Lin, Tzu-Yi	CHEN, Yong; CHANG, Jason; GANI, David; LUAN, Jing-en; CATTARINUZZI, Emanuele	Rekapalli, Vamsi (2); Mohammed, Ubed (2); V Ramana, Pamidighantam (1); Yeluripati, Rohin Kumar (1); Bhandari, Jugal Kishore (2); Dharavath, Sandhya (2)		
	Kyushu University, Japan (1)	Tamkang University, Taiwan	STMicroelectronics, Singapore	Lightspeed Photonics, Singapore		
4:20pm - 5:20pm			Exhibitors' Presentations & Lu	ickly Draw @ Riverfront II and III		
5:30pm - 7:00pm			Sponsor & Exhibitors Appreciation / N	Networking Session (by invitation only)		



			4: December 6, 2024 (Friday	,		
		Exhibition at	Waterfront Foyer from 8:30am to 4:30	Upm (Level 2)		
Venue	Waterfront I	Waterfront II	Waterfront III	Riverfront I	Riverfront II	Riverfront III
09:00am -10:20am	E1. Assembly and Manufacturing Technology 2	E2. Emerging Technologies 2	E3. Materials and Processing 3	E4. Mechanical Simulation & Characterization 3	E5. Quality, Reliability & Failure Analysis 1	E6. Silicon Interposer and Processing
	E1.1 (P1175) Investigation on Molding Void Issue in System-in-Package Module	E2.1 (P13520) CMOS compatible 2D material integration for Sensor Applications on 200mm wafers	E3.1 (P1247) Study on Microstructure and Mechanical Properties of Silver and Silver-Indium Solid Solution Films Using Magnetron Sputtering	E4.1 (P1121) Analytical K-factor Model for Monotonic Four-point Bend Test Design	E5.1 (P1164) Non-Destructive Analysis of Voiding in TIM of High- Performance Computing Devices using B-mode Scanning	E6.1 (P1207) Adaptive Pad Stacks Deliver Order of Magnitude in Bridge Die Position Tolerance in Embedded Fan-out Inter
09:00am9:20am	Yang, Chaoran; Tang, Oscar; Song, Fubin	Yoo, Tae Jin; Tezcan, Deniz Sabuncuoglu	Zhao, Shuang (1); Lin, Pengrong (2,3); Zhang, Donglin (1); Wang, Taiyu (1); Liu, Sichen (1); Xie, Xiaochen (2); Xu, Shimeng (2); Qu, Zhibo (2);	Kelly, Brian (1); Tarnovetchi, Marius (2); Newman, Keith (1)	Song, Mei Hui; Tang, Wai Kit; Tan, Li Yi	Sandstrom, Clifford Paul (1); Talain, John Erickson Apelado Jose, Benedict Arcena (1); Fang, Jen-Kuang (2); Yang, Ping- Huang, Sheng-Feng (2); Shen, Ping-Ching (2)
	Amazon, China	IMEC, Belgium	Wang, Yong (2); Zhao, Xiuchen (1); Huo, Yongjun (1,4) Beijing Institute of Technology, China (1)	AMD, USA (1)	AMD, Singapore	Deca Technologies, USA (1)
	E1.2 (P1172) Enhancing DI Water Cleanability of Tacky Flux on Cu OSP Surface Using FC Copper Pillar High-Density Interconnection	E2.2 (P1384) Hyperspectral Component Fabrication on 200mm CMOS Image Sensor Wafer	E3.2 (P1206) Versatile Photosensitive Polymer Applied in Low- Temperature Hybrid Bonding with Nanocrystalline Cu	E4.2 (P1135) Enhancing Mechanical Robustness and Integrity of a Large Advanced Package with Embedded FP Interconnect Chips	E5.2 (P1361) A Method for Die-level Fracture Toughness Evaluation by Nano-Indentation on Ring	E6.2 (P1119) Silicon Interposer Heterogenous Integration PI Millimeter Wave Ka and V band Satellite Application
9:20am - 9:40am	Lip Huei, Yam; Risson Olakkankal, Edrina; Balasubramanian, Senthil KUmar	Babu Shylaja, Tina; Yoo, Tae Jin; Geelen, Bert; Tack, Klaas; Sabuncuoglu Tezcan, Deniz	Tan, Chung-An (1); Lee, Chia-Hsin (1); Lee, Ou-Hsiang (2); Chiu, Wei- Lan (2); Chang, Hsiang-Hung (2); Yu, Shih-cheng (2)	Ji, Lin; Chai, Tai Chong	Zhu, Xintong; Rajoo, Ranjan; Nistala, Ramesh Rao; Mo, Zhi Qiang	Sun, Mei; Ong, Javier Jun Wei; Wu, Jia Qi; Lim, Sharon Pei Yong Liang; Umralkar, Ratan Bhimrao; Lau, Boon Long; Lim, Chai. Kevin Tshun Chuan
	Heraeus Materials Singapore	IMEC, Belgium	Brewer Science, Taiwan	STMicroelectronics, Singapore	Globalfoundries, Singapore	Institute of Microelectronics, Singapore
	E1.3 (P1326) Film Assisted Molding Performance Improvement with Component Design	E2.3 (P1390) Characterization of Carbon Contained Films at Bonding Interface for the Application of Backside Power Delivery Networks	E3.3 (P1286) Low temperature Ag sintering and driving force on Au finished Cu substrates at 145°C and 175°C using Ag nano-porous sheets without organic solvents	E4.3 (P1116) Study on Substrate Copper Pad Crack Through Experiment and Simulation	E5.3 (P1140) Electrostatically induced voltage generated in different type boxes of electronic equipment by moving charged object	E6.3 (P1138) Development of Large RDL Interposer Package FOWLP and 2.5D FO-Interposer
9:40am - 10:00am	Law, Hong Cheng; Lim, Fui Yee; Low, Boon Yew; Pang, Zi Jian; Bharatham, Logendran; Yusof, Azaharudin; Ismail, Rima Syafida; Lim, Denyse Shyn Yee; Lim, Shea Hui	Kitagawa, Hayato; Sato, Ryosuke; Fuse, Junya; Yoshihara, Yuki; Inoue, Furnihiro	Kim, YehRi (1,2); Yu, Hayoung (1); Noh, Seungjun (3); Kim, Dongjin (1)	Yu, Wei; Che, Fa Xing; Ong, Yeow Chon; Pan, Ling; Cheong, Wee Gee	Ichikawa, Norimitsu	Ho, Soon Wee David; Soh, Siew Boon; Lau, Boon Long; Hsi Yao; Lim, Pei Siang; Rao, Vempati Srinivasa
	NXP, Malaysia	Yokohama National University, Japan	Korea Institute of Industrial Technology (1)	Micron Semiconductor Asia Operations, Singapore	Kogakuin University, Japan	Institute of Microelectronics, Singapore
	E1.4 (P1224) An Investigation of Different Leadframe Materials with Plasma Cleaning on Extra-Large Leadframe to Study the Effects of Oxidation vs Delamination	E2.4 (P1376) Screen Printed Temperature Sensor using Novel Kish Graphite/reduced Graphene Oxide Conductive Ink for Wearable Applications.		E4.4 (P1130) Predictive Numerical Modeling of Stealth Dicing Process for Different Wafer Pre-Thin Thicknesses	E5.4 (P1350) High spatial resolution imaging of dopants and impurities for semiconductor device using NanoSIMS	E6.4 (P1209) Modeling and Fabrication of Silicon Integrat terminal Deep Trench Capacitor Technology
10:00am - 10:20am	CHUA, Yeechong; CHUA, Boowei; LEONE, Federico; LOO, Shei Meng	Rao, Ankitha (1); Bhat, Somashekara (1); De, Shounak (1); Shetty K, Nakul (1); Nayak, Ramakrishna (2)		Lim, Dao Kun (1,2); Vempaty, Venkata Rama Satya Pradeep (2); Shah, Ankur Harish (2); Sim, Wen How (2); Singh, Harjashan Veer (2); Lim, Yeow Kheng (1)	Sameshima, Junichiro; Nakata, Yoshihiko; Akahori, Seishi; Hashimoto, Hideki; Yoshikawa, Masanobu	Lin, Weida (1); Song, Changming (2); Shao, Ziyuan (3); Ma, Cai, Jian (2,4); Gao, Yuan (1); Wang, Qian (2,4)
	STMicroelectronics, Singapore	Manipal Institure of Technology, India (1)		Micron Technology, Singapore (1)	Toray Research Center, Inc, Japan	Tsinghua University, China (1)
10:20am - 10:35am			Tea Break & Exhibition (V	Vaterfront BallRoom Foyer)		
10:35am -11:55am	F1. Automotive and Power Device Packages	F2. Quality, Reliability & Failure Analysis 2	F3. Materials and Processing 4	F4. Advacned Optoelectronics	F5. Electrical Simulations & Characterization 3	F6. Thermal Management and Characterization 4
	F1.1 (P1234) A Highly Integrated AiP Design for 6G Application	F2.1 (P1184) Optimization of Aluminium Wirebonding on Niobium for Cryogenic Packaging	F3.1 (P1254) Study of Interactions between RDL Polyimides and Underfills on Reliability of Flip-Chip Interconnects in Thermal Cycling	F4.1 (P1252) Aerosol Jet Printed Encapsulation for Optoelectronics: A Study of Line Morphology	F5.1 (P1201) Effect of Decoupling Capacitor Location on PDN Impedance in fcBGA Packages	F6.1 (P1258) Thermal Characterization of LED Packages Co Wavelength Converting Phosphor Over a Large Are
10:35am -10:55am	WU, PO-I; Kuo, Hung-Chun; Jhong, Ming-Fong; Wang, Chen-Chao	Norhanani Jaafar	Chang, Hongda (1); Soriano, Catherine (1); Chen, WenHsuan (1); Yang, HungChun (2); Lai, WeiHong (2); Chaware, Raghunandan (1)	Siah, Kok Siong (1); Basu, Robin (2); Distler, Andreas (2); Häußler, Felix (1); Franke, Jörg (1); Brabec, Christoph J. (2,3,4); Egelhaaf, Hans-Joachim (2,3,4)	Song, Xiaoyuan (1); Zheng, Boyu (1,2); Luo, Jiahu (1); Wei, Ping (1); Liu, Lei (1)	Hantos, Gusztáv; Hegedűs, János; Lipák, Gyula; Németh, Má András
	ASE Group, Taiwan	Institute of Microelectronics, Singapore	Lattice Semiconductor Corp, Taiwan	Friedrich-Alexander Universität Erlangen Nürnberg, Germany (1)	Changsha Anmuquan, China (1)	Budapest University of Technology and Economics
	F1.2 (P1298) Packaging-Codesign for the development of a high- resolution MIMO-Radar-Module for Automated guided vehicles	F2.2 (P1182) In-Situ Microcrack Localization and Imaging in Laminated Die-Attachment Based on the Static Component of Ultrasonic Lamb Wayes	F3.1 (P1179)An Innovative Flux-Less Solder Ball Attachment Technology (FLAT) for Advanced BGA Assembly	F4.2 (P1341) Quantum Cascade Laser Integration with Mid-Infrared Photonic Integrated Circuits for Diverse Sensing Applications	F5.4 (P1200) A Novel Approach to Reduce Impedance Discontinuities fo High-speed Channel in IC Packages	r F6.2 (P1289) Numerical Optimization of PCM-Based Heat Thermal Management of High-power-density Electron
10:55am - 11:15am	Tschoban, Christian; Pötter, Harald	Long, Xu (1); Li, Yaxi (2); Wang, Jishuo (3); Zhao, Liang (3); Yuan, Weifeng (3)	Kim, Dongjin (1); Han, Seonghui (1,3); Han, Sang Eun (1,4); Choi, Dong- Gyu (1,5); Chung, Kwansik (2); Kim, Eunchae (2); Yoo, Sehoon (1)	Kannojia, Harindra Kumar (1): Zhai, Tingting (1); Maulini, Richard (2); Gachet, David (2); Kuyken, Bart (1); Van Steenberge, Geert (1)	Luo, Jiahu (1); zheng, Boyu (1,2); Song, Xiaoyuan (1); Jiang, Bo (1); Lee SooLim (1)	HU, RAN (1,2); Du, Jianyu (2); Shi, Shangyang (1,2); Lv, Pé Cao, Huiquan (2); Jin, Yufeng (1,2); Zhang, Chi (2,3,4); W (2,3,4)
	Fraunhofer IZM, Germany	Northwestern Polytechnical University, China	Korea Institute of Industrial Technology (1)	IMEC, Belgium (1)	Changsha Anmuquan, China	Peking University, China
	F1.3 (P13060) Robustness Methodology for Next Generation Automotive Microcontroller Flip Chip Copper Pillar Technologies	F2.3 (P1122) BLR Drop Test Study for FCCSP Package with OSP/Cu Solder Pad finish	F3.3 (P1281) Elimination of Parametric Shifts in Trench MOSFETs Using Low Alpha-Particle Solder	F4.3 (P1328) III-V Laser Diode Flip Chip Bonding on Photonics Integrated Circuit with SnAg Solder	F5.3 (P1304) Full-Wave Electromagnetic Simulation Approach for Integrated 3D-IC Design	F6.3 (P1269) Heat-Resistant Reliability of Large Area Silver Connections for Direct Cooling in Power Inverter Applic
	Tan, Aik Chong; Bauer, Robert; Rau, Ingolf; Doering, Inga	Liu, Jinmei	Gajda, Mark A. (1); de Leon, Charles Daniel T. (2); A/P Ramalingam, Vegneswary (3); Santican, Haima (3)	Chi, Ting Ta (1); Ser Choong, Chong (1); Lee, Wen (1); Yuan, Xiaojun (2)	Jaiswal, Anushruti; Patil, Tejkiran; Dhanekula, Mahesh Babu	Yu, HaYoung; Kim, Seoah; Kim, Dongjin
11:15am - 11:35am	ran, rat onong, bador, nober, naa, ingon, booring, inga			Institute of Microelectronics, Singapore (1)	Ansys, India	Korea Institute of Industrial Technology
11:15am - 11:35am	Infineon Technologies, Singapore	NXP Semiconductor Company, China	Nexperia, United Kingdom			
11:15am - 11:35am		NXP Semiconductor Company, China F2.4 (P1236) Influence of Material Composition on Copper-aluminum Wire Bonding Reliability	Nexperia, United Kingdom F3.4 (P1218) Effects of Bi contents in Sn–5Ag lead-free solders on mechanical properties and morphology of IMC	F4.4 (P1128) Generation of Beam Profiles from Chip-to-Free-Space Coupling using Deep Neural Network	F5.2 (P1162) Discussion on the Electrical Characteristics of Tera-Hz in Organic Substrate	F6.4 (P1199) A Study on Thermal Performance Enhanceme chip Power µModules
11:15am - 11:35am 11:35am - 11:55pm	Infineon Technologies, Singapore F1.4 (P1387) Bond Strength Comparison of Commercial and Custom	F2.4 (P1236) Influence of Material Composition on Copper-aluminum Wire Bonding Reliability Carluccio, Roberta (1): Caglio, Carolina (1): Alesi, Mirko (1): Mancaleoni,	F3.4 (P1218) Effects of Bi contents in Sn–5Ag lead-free solders on			Dai, Qiaobo (1); Liu, Zhen (1); Liao, Linjie (2); Zheng, Bo
	Infineon Technologies, Singapore F1.4 (P1387) Bond Strength Comparison of Commercial and Custom Copper Sinter Pastes under Sinter Process Modifications Meyer, Meyer, Gierth, Karl Felix Wendelin, Meier, Karsten; Bock,	F2.4 (P1236) Influence of Material Composition on Copper-aluminum Wire Bonding Reliability	F3.4 (P1218) Effects of Bi contents in Sn-5Ag lead-free solders on mechanical properties and morphology of IMC Liu, Kuan Cheng: Li, Chuan Shun; Teng, Wen Yu; Hung, Liang Yih;	Coupling using Deep Neural Network	Organic Substrate	chip Power µModules



I Debonding for Chip Stacking Applications yita; Vasarla, Nagendra Sekhar; Venkataraman, Nandini Institute of Microelectronics, Singapore	Waterfront II G2. Wafer Processing and Characterization 2 G2.1 (P1411) Patterning of 1µm Critical Dimension Through Silicon Via using Positive Tone Resist Mask by a Photolithography Stepper Sundaram, Arvind (1); Kang, Riley (2); Bhesetti, Chandra Rao (1) Institute of Microelectronics, Singapore (1) G2.2 (P1410) Nichium: Isst Process for Multi-foundry-compatible Wafer Level Processing of Superconducting Interposers Goh, Simon Chun Kiat; Mg, Yong Chyn; Ong, Javier Jun Wei; Lau, Danieir, Tseng, Ya-Ching; Jaafar, Norhanani; Yoo, Jae Ok; Liu, Liyuan; Teo, Everline Shu Yun; Chua, Micholas Boon Leong; Li, Hongyu Institute of Microelectronics, Singapore G2.3 (P1331) A New D2W Bonding Alignment Scheme using Magnetic and Capiliary assisted Self-alignment Choi, Daesan (1); Kim, Sumin (2); Hahn, Seung Ho (1); Moon, Bumki (1), Rhee, Daniel Mirmoo (1) Samsung Electronics, South Korea	Level Packaging through Novel PVD Processing	Riverfront I G4. Smart Manufacturing, Equipment & Tooling Co-Design G4. 1 (P1308) Exploring Diffusion Model for Semiconductor Defect Detection Lu, Kangkang: Cal, Lile: XU, Xun: Pahwa, Ramanpreet; Wang, Jie: Chang, Richard: Foo, Chuan-Sheng Institute for Inflocomm Research, Singapore G4.2 (P1287) End-to-end Fast Segmentation Framework for 3D Visual Inspection of HBMs Wang, Jie (1): Chang, Richard (1): Lin, Mang Keong (2): Chong, Ser Choorg (2): Yang, Xulei (1): Palwa, Ramanpreet Singh (1) Institute for Infocomm Research, Singapore (1) G4.3 (P1375) Ultra-thin ta-C Hermetic Seals for Electronics Packaging Phua, Eric Jian Rong; Lim, Song Kiat Jacob; Tan, Yik Kai; Shi, Xu Nanofilm Technologies, Singapore G4.4 (P12510 Semiconductor MEMS Waferbond Defect Detection: The Industrial Application of ResNets Stoll, Fiete; Dubey, Vikas; Wünsch, Dirk; Roscher, Frank; Wiemer, Maik	Nguyen, Bich-Yen (2) Institute of Microelectronics. Singapore G5.3 (P1285) Fabrication of Through Alumina Vias: A Cost-effective Alternative Approach Using Ultrasonic Machining and Electroless Deposition Pawar, Karan; Pandey, Harsh; Dixit, Pradeep Indian Institute of Technology Bombay G5.4 (P1109) Electrical Characterization and Reliability Studies of TSI with 5-layer Frontside Cu and 2-layer Backside Cu RDL	Riverfront III G6. Embedded and Fan-Out Packaging G6.1 (P1202) Integration Module of Dual MOSFET Switching Cir Using Embedded Silicon Fan-Out (eSIFO®) Technology Olang, Wenbin: Zhang, Xiangou; Sun, Xiangyu; Deng, Shuairon Yang, Zhenzhong Microsystem and Terahertz Research Center, China G6.2 (P1268) Corrosion behavior of aluminium pads in Fan-Out P Level Packaging (FOPLP) Yu, Yeonseop (1): Park, Seycon (2); Kim, Miyang (2); Moon, Taeh Samsung Electronics, South Korea (1) G6.3 (P1123) Comparison of Electrical, Thermat, and Mechanic Performances of a fcBGA with that of a Fan-Out SiPlet Packag Ouyang, Eric; Ahn, Billy; Han, Bi; Han, Michael; Kang, Chen; O Michael Silicon Box G6.4 (P1228) Fan-Out Packaging without Warpage Schindler, Markus; Ringelsteter, Severin; Bues, Martin; Kreul, Ki			
S1. Bonding & Debonding Processes High-temp-stable temporary bond adhesive for IR laser genables new process integration for thin wafers (1): kurnar, Amit (1): Brandt, Elisabeth (2): Bravin, Julian (2): Prever Science, United Kingdom (1) S0) Delamination of Temporary Bonded Wafers: A Comprehensive Study Jedidi, Nader IMEC, Beigium rface Quality Challenges Associated with Temp Bonding Debonding for Chip Stacking Applications pria: Vasarla, Nagendra Sekhar; Venkataraman, Nandini Institute of Microelectronics, Singapore ting overlay control towards 2.5/30 system integration in backnet lifturgaryhurg (2): wan der Stam, Kinchiel (1) (1). Chang, Hälang-Hung (2): wan der Stam, Kinchiel (1)	G2. Wafer Processing and Characterization 2 G2.1 (P1411) Patterning of 1µm Critical Dimension Through Silicon Via using Positive Tone Resist Mask by a Photolithography Stepper Sundaram, Arvind (1); Kang, Riley (2); Bhesetti, Chandra Rao (1) Institute of Microelectronics, Singapore (1) G2.2 (P1410) Niobium: Isst Process for Multi-foundry-compatible Wafer Level Processing of Superconducting Interposers Goh, Simon Chun Kiat; Kg, Yong Chyn; Ong, Javier Jun Wei; Lau, Daniel; Tseng, Ya-Ching; Jasifar, Norhanani; Yoo, Jae Ok; Liu, Lyuan; Teo, Everline Shu Yun; Chun, Micholas Boon Leong; Li, Hongyu Institute of Microelectronics, Singapore G2.3 (P1331) A New D2W Bonding Alignment Scheme using Magnetic and Capillary assisted Self-alignment Choi, Daesan (1); Kim, Sumin (2); Hahn, Soung Ho (1); Moon, Bumki (1); Rhee, Daniel Minwoo (1) Samsung Electronics, South Korea G2.4 (P1233) Novel Wet-Chemical Processing for Sidewall Plating of High Reliability Bottom-Terminated Packages Hovestad, Arjan (1); Basu, Tarun (2)	G3. Materials and Processing 5 G3.1 (P1198) Influence of Flow Rate and Current Density on Copper Deposition in Through Hole Zeng, Barry; Ye, Rick; Pai, Yu-Cheng; Wang, Yu-Po Siliconware Precision Industries Co., Ltd., Talwan G3.2 (P1156) Routable Wettable Flanks for MEMS devices Shaw, Mark; Gritti, Alex; Ratti, Andrea; Wong, Kim-Sing; Loh, Hung- meng; Casati, Alessandra; Antilano Jr, Ernesto; Soreda, Alvin STMicroelectronics, Italy G3.3 (P1183) Understanding and Improving Rc Management for Wafer Level Packaging through Novel PVD Processing Barker, Anthony James; Haymore, Scott; Willy, Tony; Rastogi, Amit; Moncrieff, Ian; Jones, Steve; Joanne Chuan Sun KLA-Tencor, United Kindom G3.4 (P1240) Dielectric Breakdown of In-Package Epory Mold Compound under Wet and Dry Conditions. Frequency and Temperature dependence Balestra, Luigi (1); Riaz, Mihama Tarwer (1); Guilano, Faderico (1); Cavalini, Andrea (1); Reagain, Sussanna (1); Oldian, Luca (2); Guanreiro, Sinnone Sadvaro (2); Rossett, Mattia (2); Depento, Riccardo (2)	G4. Smart Manufacturing, Equipment & Tooling Co-Design G4.1 (P1309) Exploring Diffusion Model for Semiconductor Defect Detection Lu, Kangkang: Cai, Lile; XU, Xun; Pahwa, Ramanpreet; Wang, Jie; Chang, Richard; Foo, Chuan-Sheng Institute for Infocomm Research, Singapore G4.2 (P1287) End-to-end Fast Segmentation Framework for 3D Visual Inspection of HBMs Wang, Jie (1); Chang, Richard (1); Lin, Mang Keong (2); Chong, Ser Choong (2), Yang, Xulei (1); Palwa, Ramanpreet Singh (1) Institute for Infocomm Research, Singapore (1) G4.3 (P1376) Ultra-thin ta-C Hermetic Seals for Electronics Packaging Phua, Eric Jian Rong; Lim, Song Kiat Jacob; Tan, Yik Kai; Shi, Xu Nanofilm Technologies, Singapore G4.4 (P12510 Semiconductor MEMS Waferbond Defect Detection: The Industrial Application of ResNets Stoll, Fiete; Dubey, Vikas; Wünsch, Dirk; Roscher, Frank; Wiemer, Maik	G5. TSV and Wafer Level Packaging 3 G5.1 (P1180) Optimization of High Aspect Ratio Copper Pillar Fabrication for Through Mold Interposer (TMI) Processing Peh, Cun Jue; Lau, Boon Long; Chia, Lai Yee; Ho, Soon Wee. Institute of Microelectronics, Singapore G5.2 (P1405) Splitting Process Integration for 2.5D/3D Packaging Li, Hongyu (1); Vasaria Nagendra, Sekhar (1); Schwarzenbach, Watter (2); Besnard, Guillaume (2); Lin, Sharon (1); BEN MOHAMED, Nadia (2); Nguyen, Bich-Yen (2) Institute of Microelectronics, Singapore G5.3 (P1285) Fabrication of Through Alumina Vlas: A Cost-effective Alternative Approach Using Ultrasonic Machining and Electroless Daposition Pawar, Karan; Pandey, Harsh; Dixit, Pradeep Indian Institute of Technology Bombay G5.4 (P1109) Electrical Characterization and Reliability Studies of TSI with 5-layer Frontside Cu and 2-layer Backside Cu RDL	G6. Embedded and Fan-Out Packaging G6.1 (P1202) Integration Module of Dual MOSFET Switching Cir Using Embedded Silicon Fan-Out (eSiFOB) Technology Olang, Wenbin; Zhang, Xiangou; Sun, Xiangyu; Deng, Shuairon Yang, Zhenzhong Microsystem and Terahertz Research Center, China G6.2 (P1268) Corrosion behavior of aluminium pads in Fan-Out P Level Packaging (FOPLP) Yu, Yeonseop (1): Park, Seyoon (2): Kim, Miyang (2): Moon, Taeh Samsung Electronics, South Korea (1) G6.3 (P1123) Comparison of Electrical, Thermal, and Mechanic Performances of a EleGA with that of a Fan-Out SiPet Packag Ouyang, Eric; Ahn, Billy; Han, BJ; Han, Michael; Kang, Chen; O Michael Silicon Box G6.4 (P1228) Fan-Out Packaging without Warpage Schindler, Markus; Ringelstetter, Severin; Bues, Martin; Kreul, Kil			
High-temp-stable temporary bond adhesive for IR laser High-temp-stable temporary bond adhesive for IR laser grables new process integration for thin wafers (1): kumar, Amit (1): Brandt, Elisabeth (2): Bravin, Julian (2): Peter (2): Geier, Roman (3): Siegert, Joerg (3) Brewer Science, United Kingdom (1) 50) Delamination of Temporary Bonded Wafers: A Comprehensive Study Jedidi, Nader IMEC; Belgium rface Quality Challenges Associated with Temp Bonding I Debonding for Chip Stacking Application (1) Elisabeth (2): Stacking Application (1) Stacking Application, Singapore Ung overfay control towards 2.5/3D system integration in backend lithography processes hing (1): Lee, Yutai (1): Lee, Yuan-Chang (2): van der (1): Chang, Haisn-Hung (2): van der Stam, Michiel (1)	G2.1 (P1411) Patterning of 1µm Critical Dimension Through Silicov Via using Positive Tone Resist Mask by a Photolithography Stepper Sundaram, Arvind (1); Kang, Riley (2); Bhesetti, Chandra Rao (1) Institute of Microelectronics, Singapore (1) G2.2 (P1410) Niobium- last Process for Multi-foundry-compatible Wafer Level Processing of Superconducting Interposers Goh, Simon Chun Kitt, Yag, Yong Chym, Cng, Javier Jun Wei, Luy, Daniet, Tseng, Ya-Ching, Jadier, Korhanari, Yoo, Jae Ok, Liu, Lyuan; Teo, Evertine Shu Yan; Chua, Nicholas Boon Leong; Li, Hongyu Institute of Microelectronics, Singapore G2.3 (P1331) A New D2W Bonding Alignment Scheme using Magnetic and Capillary assisted Self-alignment Choi, Daesan (1); Kim, Sumin (2); Hahn, Seung Ho (1); Moon, Bumki (1); Rhee, Daniel Mirwoo (1) Samsung Electronics, South Korea G2.4 (P1233) Novel Wet-Chemical Processing for Sidewall Plating of High Reliability Bottom-Terminated Packages Hovestad, Arjan (1); Basu, Tarun (2)	G3.1 (P1198) Influence of Flow Rate and Current Density on Copper Deposition in Through Hole Zeng, Barry; Ve, Rick; Pai, Yu-Cheng; Wang, Yu-Po Siliconware Precision Industries Co., Ltd., Taiwan G3.2 (P1156) Routable Wettable Flanks for MEMS devices Shaw, Mark; Gritti, Alex; Ratti, Andrea: Wong, Kim-Sing; Loh, Hung- meng; Casati, Alessandra; Antiano Jr, Ernesto; Soreda, Alvin STMicroelectronics, Italy G3.3 (P1183) Understanding and Improving Re Management for Wafer Level Packaging through Novel PVD Processing Barker, Anthony James; Haymore, Scott; Wilby, Tony; Rastogi, Amit; Moncrieff, Ian; Jones, Steve; Joanne Chuan Sun KLA-Teincor, United Kindom G3.4 (P124) Dielectic Braddown of m-Package Epoxy Mold Compound under Wet and Dry Conditions: Frequency and Temperature dependence Balestra, Luigi (1); Riaz, Mahammad Tarweer (1); Gluilano, Federico (1); Cavaillin, Andrea (1); Reggiani, Sasanna (1); Oldinni, Luca (2); Guannera, Simone Balestra, Luigi (1); Riaz, Mahammad Tarweer (1); Gluilano, Federico (2); Cavaillin, Andrea (1); Reggiani, Sasanna (1); Oldinni, Luca (2); Guannera, Simone Balestra, Luigi (1); Riaz, Mahamat Carboner (1); Gluilano, Federico (2); Cavaillin, Andrea (1); Reggiani, Sasanna (1); Oldinni, Luca (2); Guannera, Simone Balestra, Luigi (1); Riaz, Mahammad Tarweer (1); Gluilano, Federico (2); Cavaillin, Andrea (2); Respiration; Mattio (2); Despiro, Riccardo (2); Cavaillin, Andrea (2); Respiration; Respirations (2); Guannera, 2); Simone Balestra, Luigi (1); Riaz, Mahamad Tarweer (1); Gluilano, Federico (2); Cavaillin, Andrea (2); Respiration; Mattio (2); Despiro, Riccardo (2); Guannera, 2); Simone Balestra, Luigi (1); Riaz, Mahamad Tarweer (1); Gluilano, Federico (1); Cavaillin, Andrea (2); Respiration; Mattio (2); Despiration; Respiration (2); Guannera, 2); Simone Balestra, Luigi (1); Riaz, Mahamad Carbus (1); Routanio, 2); Guannera, 2); Simone Balestra, Luigi (1); Riaz, Mahamad Carbus (2); Suannera, 2); Simone Balestra, Luigi (1); Riaz, Mahamad Carbus	G4.1 (P1309) Exploring Diffusion Model for Semiconductor Defect Detection Lu, Kangkang: Cai, Lile; XU, Xun; Pahwa, Ramanpreet; Wang, Jie; Chang, Richard; Foo, Chuan-Sheng Institute for Inflocomm Research, Singapore G4.2 (P1287) End-to-end Fast Segmentation Framework for 3D Visual Inspection of HBMs Wang, Jie (1): Chang, Richard (1): Lim, Meng Keong (2): Chong, Ser Choong (2): Yang, Xulei (1): Pahwa, Ramanpreet Singh (1) Institute for Inflocomm Research, Singapore (1) G4.3 (P1375) Ultra-thin ta-C Hermetic Seals for Electronics Packaging Phua, Eric Jian Rong: Lim, Song Kiat Jacob; Tan, Yik Kai; Shi, Xu Nanofilm Technologies, Singapore G4.4 (P12510 Semiconductor MEMS Waferbond Defect Detection: The Industrial Application of ResNets Stoll, Fiete; Dubey, Vikas; Wünsch, Dirk; Roscher, Frank; Wiemer, Maik	G5.1 (P1180) Optimization of High Aspect Ratio Copper Pillar Fabrication for Through Mold Interposer (TMI) Processing Peh, Cun Jue; Lau. Boon Long; Chia, Lai Yee; Ho, Soon Wee. Institute of Microelectronics. Singapore G5.2 (P1405) Splitting Process Integration for 2.5D/3D Packaging Li, Hongyu (1); Vasaria Nagendra, Sekhar (1); Schwarzenbach, Walter (2); Besnard, Guillaume (2); Lim, Sharon (1); Beth MOHAMED, Nadia (2); Nguyen, Bich-Yen (2) Institute of Microelectronics. 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Onto Innovation, Taiwan (1)	Besi, The Netherland	University of Bologna, Italy (1)						
			ENAS Fraunhofer, Germany	Institute of Microelectronics, Singapore	Delo, Germany			
		Tea Break & Exhibition	(Grand Ballroom Foyer)					
Waterfront I	Waterfront II	Waterfront III	Riverfront I	Riverfront II	Riverfront III			
ssembly and Manufacturing Technology 3	H2. Quality, Reliability & Failure Analysis 3	H3. Materials and Processing 6	H4. Mechanical Simulation & Characterization 4	H5. Package Design and Characterization for Al Applications	H6. Flip Chip and Fan-Out on Substrate			
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e, Matthias; Fisch, Anne; Teutsch, Thorsten	Yang, Yongbo; Yong, Eric; Qiu, Wen	Sharma, Jaibir; Qing Xin, Zhang	Long, Xu (1); Hu, Yuntao (2); Shi, Hongbin (3); Su, Yutai (2)	Ser Choong Chong	Lai, Chung-Hung			
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sposo; Tabiera, Michael Tabiera; Gomez, Frederick Ray Gomez	Muralionaran Nair, Shyam (1); Tran, Khann (1); Chyan, Oliver (1); Polian,	Shaw, Mark; Simoncini, Daniele; Duca, Roseanne; Falorni, Luca; Carulli, Paola; Fedeli, Patrick; Brignoli, Davide	Albrecht, Jan (1,2); Rzepka, Sven (1,2)	Shangguan, Dongkai (1); Yang, Cheng (2); Hang, Yin (3)	Lin, I-Hung (1); Shih, Meng-Kai (2); Ding, Bo-Rui (2); Lou, Bai-Ya Ni, Tom (1)			
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efferson; Tabiera, Michael; Graycochea Jr, Edwin	Lee, Jun Ho (1); Joo, Ji Yong (1); Lee, Jun Sung (1); Kim, Se Jeong (1); Kwon, Oh-Hyung (2)	Danila, Bayaras, Abito; Balasubramanian, Senthil Kumar	Zhao, Facheng; Zhu, Liping; Yeo, Alfred	Graening, Alexander Phillip (1); Patel, Darayus Adil (2); Sisto, Giuliano (2); Lenormand, Erwan (2); Perumkunnil, Manu (2); Pantano, Nicolas (2); Kumar Vinav B Y (2): Gunta Puneet (1): Mallik, Arindam (2)	Rongrong Jiang; Trent Uehling, Bihua He; Tingdong Zhou; Mei Song; Azham Mohdsukemi; Taki Fang, Roy Lo; Kaelin Wan			
STMicroelectronics, Philippines	Kongju National University, South Korea	Heraeus Materials Singapore	STATS ChipPAC Singapore	UCLA, USA (1)	NXP Semiconductor Company, China			
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